

(30) Priority Data:

WORLD INTELLECTUAL PROPERTY ORGANIZATION International Bureau



INTERNATIONAL APPLICATION PUBLISHED UNDER THE PATENT COOPERATION TREATY (PCT)

WO 97/10698 (11) International Publication Number: (51) International Patent Classification⁶: A3 27 March 1997 (27.03.97) (43) International Publication Date: G01P 15/00

US

PCT/US96/14131 (21) International Application Number:

3 September 1996 (03.09.96) (22) International Filing Date:

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5 September 1995 (05.09.95)

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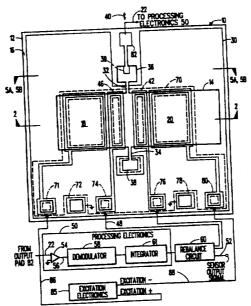
(81) Designated States: CA, JP, European patent (AT, BE, CH, DE, DK, ES, FI, FR, GB, GR, IE, IT, LU, MC, NL, PT, SE).

Published

With international search report. Before the expiration of the time limit for amending the claims and to be republished in the event of the receipt of amendments.

(88) Date of publication of the international search report: 17 April 1997 (17.04.97)

(54) Title: MICROMECHANICAL SENSOR WITH A GUARD BAND ELECTRODE AND FABRICATION TECHNIQUE THEREFOR



(57) Abstract

An electrostatically actuated micromechinical sensor (10) having a guard band electrode (30) for reducing the effect of transients associated with a dielectic substrate (12) of the sensor. A proof mass (14), responsive to an input, is suspended over the substrate and one or more electrodes (18, 20) are disposed on the substrate in electrostatic communication with the proof mass to sense the input acceleration and/or torque the proof mass back to the null position. The guard band electrode is disposed over the dielectric substrate in overlapping relationship with the electrodes and maintains the surface of the substrate at a reference potential, thereby shielding the proof mass from transients and enhancing the accuracy of the sensor. A dissolved wafer process for fabricating the sensor is described, in which the proof mass is defined by boron doping. An alternative fabrication technique is also described in which the proof mass is defined by an epitaxial layer.

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INTERNATIONAL SEARCH REPORT

International application No. PCT/US96/14131

A. CLASSIFICATION OF SUBJECT MATTER							
IPC(6) :G01P 15/00							
US CL:073/514.36 According to International Patent Classification (IPC) or to both national classification and IPC							
B. FIELDS SEARCHED							
Minimum documentation searched (classification system followed by classification symbols)							
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C. DOC	CUMENTS CONSIDERED TO BE RELEVANT		Relevant to claim No.				
Category*	Citation of document, with indication, where ap	propriate, of the relevant passages	Relevant to clant 140.				
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INTERNATIONAL SEARCH REPORT

International application No. PCT/US96/14131

B. FIELDS SEARCHED

Minimum documentation searched Classification System: U.S.

073/514.16, 514.17, 514.18, 514.23, 514.32, 514.36, 777; 257/415; 310/309; 324/687, 688; 361/280, 283.1, 283.2, 283.3, 283.4, 290, 291; 437/148, 228SEN, 901, 921, 927, DIG159

B. FIELDS SEARCHED

Electronic data bases consulted (Name of data base and where practicable terms used):

USPTO APS

search terms: silicon, substrate, mass, weight, proof, pendulum, electrode, terminal, pad, epitaxial, glass, layer, plate, wafer, sensor, accelerometer